

IN THE CLAIMS:

Please amend Claims 5 and 9 as shown below.

1. (Cancelled)

2. (Previously Presented) The method according to claim 5, wherein said metal compound is an organometallic compound.

3. (Previously Presented) The method according to claim 5, wherein the total content of the elemental halogens, halogen ions and halogen compounds contained in said sol-gel composition is 3 ppm or less.

4. (Previously Presented) The method according to claim 5, wherein said dispersoid comprises at least titanium, zirconium and lead.

5. (Currently Amended) A method of manufacturing a piezoelectric film, comprising:

a process for preparing, by performing a plurality of preparation purification operations at different times, a sol-gel composition for forming a piezoelectric element, wherein the total content of the elemental halogens, halogen ions and halogen compounds contained in said sol-gel composition is 10 ppm or less, and wherein the sol-gel composition comprises a dispersoid obtained from a metal compound;

a process for forming a coating film by coating a substrate with said sol-gel composition;

a process for drying said coating film; and
a process for obtaining said piezoelectric film by baking said dried coating
film.

6. (Original) A piezoelectric element comprising a piezoelectric film
sandwiched between a lower electrode and an upper electrode, wherein said piezoelectric
film is produced by the method according to claim 5.

7. (Previously Presented) The piezoelectric element according to claim 6,
wherein the total content of the elemental halogens, halogen ions and halogen compounds
contained in said piezoelectric film is 10 ppm or less.

8. (Previously Presented) An ink jet recording head, comprising a pressure
chamber communicated with an ink jet orifice, a vibrating plate arranged in a manner
corresponding to said pressure chamber, the piezoelectric element according to claim 6
arranged in a manner corresponding to said vibrating plate, wherein the ink in said pressure
chamber is jetted from said ink jet orifice owing to a volume change within said pressure
chamber caused by said piezoelectric element arranged in a manner corresponding to said
vibrating plate.

9. (Currently Amended) The method according to claim 5, wherein said
plurality of preparation purification operations comprises different preparation purification
operations.